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Pages:64 - 70

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**5 DCS-1: a fuzzy logic expert system for automatic defect classificati
semiconductor wafer defects**

Luria, M.; Moran, M.; Yaffe, D.; Kowski, J.;

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DCS-1: a fuzzy logic expert system for automatic defect classification of semiconductor wafer defects

[Luria, M.](#) [Moran, M.](#) [Yaffe, D.](#) [Kawski, J.](#)

Galai Lab., Migdal Haemek, Israel ;

This paper appears in: Fuzzy Systems, 1994. IEEE World Congress on Computational Intelligence., Proceedings of the Third IEEE Conference

Meeting Date: 06/26/1994 - 06/29/1994

Publication Date: 26-29 June 1994

Location: Orlando, FL USA

On page(s): 2100 - 2106 vol.3

Reference Cited: 7

Inspec Accession Number: 4840557

Abstract:

DCS-1, a defect **classification** system for classifying defects on a **semicond** wafers using a builtin fuzzy logic expert system is described. DCS-1 is advant manual **classification** because it is both **objective** and fast. Defect **classes** using DDL (Defect Description Language), a language of fuzzy predicates whi developed for this application. The paper describes a unique approach to fuzz image processing where fuzzy features are computed using traditional image techniques and **classifications** are decided using fuzzy logic rules

Index Terms:

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